



2125 JFW

In re Application of:

Docket No. 00862.022239

SHIGEYUKI UZAWA, ET AL.

Application No.: 09/864,309

Examiner: Ryan A. Jarrett

Filed: May 25, 2001

Group Art Unit: 2125

For: EXPOSURE APPARATUS, COATING/
DEVELOPING SYSTEM, DEVICE
MANUFACTURING SYSTEM, DEVICE
MANUFACTURING METHOD,
SEMICONDUCTOR MANUFACTURING
FACTORY, AND EXPOSURE APPARATUS
MAINTENANCE METHOD

November 10, 2004

Mail Stop Amendment

Commissioner For Patents

P.O. Box 1450

Alexandria, Virginia 22313-1450

Sir:

Transmitted herewith is an Amendment in the above-identified application.

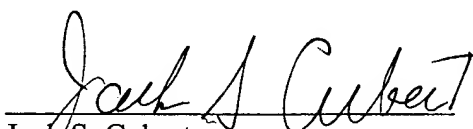
☒ No additional fee is required.

The fee has been calculated as shown below:

CLAIMS AS AMENDED						
	(2) CLAIMS REMAINING AFTER AMENDMENT		(4) HIGHEST NO. PREVIOUSLY PAID FOR	(5) PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL CLAIMS	14	MINUS	47	= 0	x \$9 \$18	0.00
INDEP. CLAIMS	1	MINUS	9	= 0	x \$43 \$88	0.00
Fee for Multiple Dependent claims \$150/\$300						0.00
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT---						0.00

- ☐ °Verified Statement claiming small entity status is enclosed, if not filed previously.
- ☐ A check in the amount of \$____ is enclosed.
- ☐ Charge \$____ to Deposit Account No. 06-1205. A duplicate copy of this sheet is enclosed.
- ☒ Any prior general authorization to charge an issue fee under 37 C.F.R. 1.18 to Deposit Account No. 06-1205 is hereby revoked. The Commissioner is hereby authorized to charge any additional fees under 37 C.F.R. 1.16 and 1.17 which may be required during the entire pendency of this application, or to credit any overpayment, to Deposit Account No. 06-1205. A duplicate copy of this paper is enclosed.
- ☐ A check in the amount of \$____ to cover the fee for a ____ month extension is enclosed.
- ☐ A check in the amount of \$____ to cover the Information Disclosure Statement fee is enclosed.
- ☒ Applicants' attorney, Steven E. Warner, may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.

Respectfully submitted,



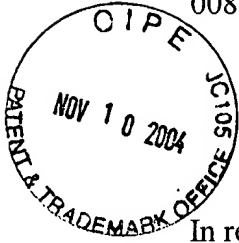
Jack S. Cubert
Attorney for Applicants
Registration No. 24,245

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SEW/JSC/dc

DC_MAIN 184065v1

00862.022239

PATENT APPLICATION



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
SHIGEYUKI UZAWA, ET AL.)
Application No.: 09/864,309)
Filed: May 25, 2001)
For: EXPOSURE APPARATUS,)
COATING/DEVELOPING SYSTEM :
DEVICE MANUFACTURING SYSTEM,)
DEVICE MANUFACTURING METHOD, :
SEMICONDUCTOR MANUFACTURING)
FACTORY, AND EXPOSURE :
APPARATUS MAINTENANCE METHOD) November 10, 2004

Examiner: Ryan A. Jarrett
Group Art Unit: 2125

Mail Stop Amendment
COMMISSIONER FOR PATENTS
P.O. Box 1450
Alexandria, Virginia 22313-1450

AMENDMENT

Sir:

In response to the Office Action dated August 10, 2004, please amend the above identified application as follows: